# PROCEEDINGS OF SPIE

# Optical Design and Testing IV

Yongtian Wang Julie Bentley Chunlei Du Kimio Tatsuno Hendrik P. Urbach Editors

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Sandy To, The Hong Kong Polytechnic University (Hong Kong, China)

**Theo Tschudi**, Technische Universität Darmstadt (Germany)

Wilhelm Ulrich, Carl Zeiss SMT AG (Germany)

### Session Chairs

Novel Optical System Design I
 Kimio Tatsuno, Hitachi, Ltd. (Japan)

- 2 Fabrication and Testing Julie Bentley, The Institute of Optics, University of Rochester (United States)
- 3 Aberration Theory and Image Analysis Yongtian Wang, Beijing Institute of Technology (China)
- 4 Optical Measurement
  Changsheng Li, BeiHang University (China)
- Nonimaging Optics and Illumination Optics
   Hong Liu, Zhejiang University of Technology (China)
- Display System Design Jannick P. Rolland, The Institute of Optics, University of Rochester (United States) and The College of Optics and Photonics, Univ. of Central Florida (United States)
- Novel Optical System Design IIHongbo Xie, Tianjin University (China)
- LED Illumination Systems
   Hong Wang, South China University of Technology (China)
- 9 Metamaterial Design and Novel Photonics Devices Chunlei Du, Institute of Optics and Electronics (China)
- Interferometry in Optical TestingJian Bai, Zhejiang University (China)